

Status of EUDET Prototype

An Attempt to give/get an Overview



Roman Pöschl
LAL Orsay



- Status of Mechanical Construction
- Status of Wafer Production and Electronics Development
- Interplay between different components (interleaved)
- Plans for 2008

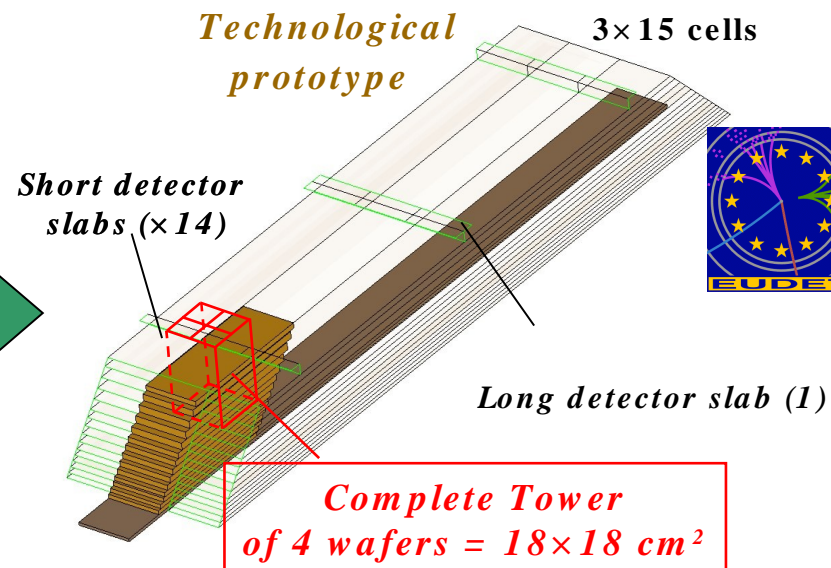
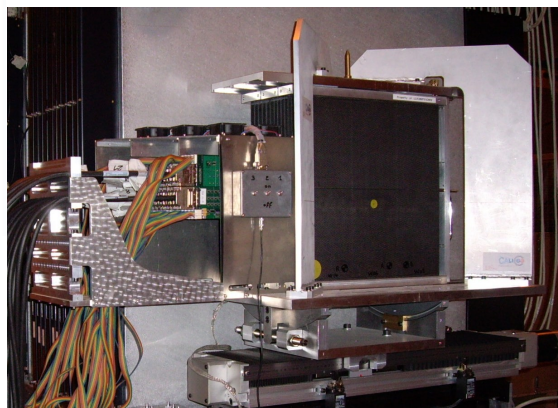
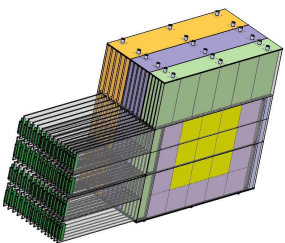
Material for this presentation courtesy of:

Marc Anduze, Denis Grodin, Ray Thomson, Julien Fleury
Maurice Goodrick, Laurent Royer



EUDET Prototype

- **Logical continuation** to the physical prototype study which validated the main concepts : alveolar structure , slabs, gluing of wafers, integration
- Techno. Proto : study and validation of most of **technological solutions** wich could be used for the final detector (moulding process, cooling system, wide size structures,...)
- Taking into account **industrialization aspect** of process
- First **cost** estimation of one module



- **3 structures : 24 X₀**
(10×1,4mm + 10×2,8mm + 10×4,2mm)
- **sizes : 380×380×200 mm³**
- **Thickness of slabs : 8.3 mm**
(W=1,4mm)
- **VFE outside detector**
- **Number of channels : 9720**
(10×10 mm²)
- **Weight : ~ 200 Kg**

Collabora

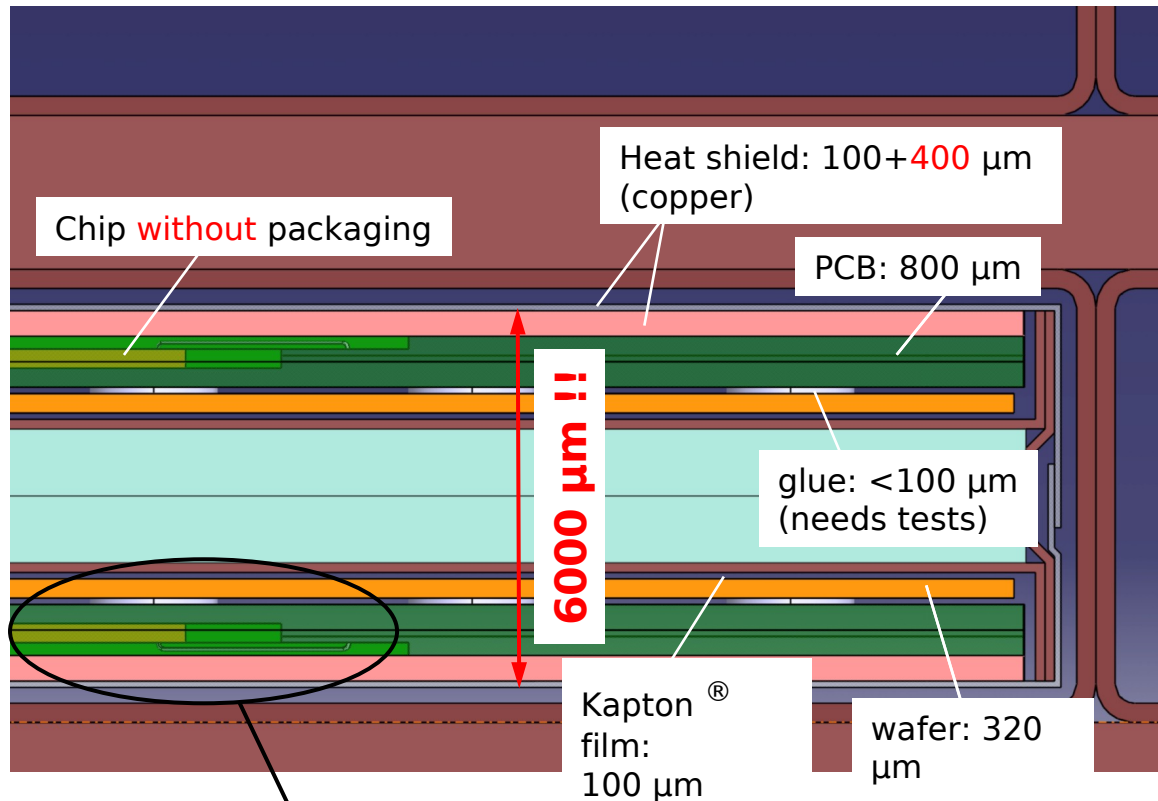
- **1 structure : ~ 23 X₀**
(20×2,1mm + 9×4,2mm)
- **sizes : 1560×545×186 mm³**
- **Thickness of slabs : 6 mm**
(W=2,1mm)
- **VFE inside detector**
- **Number of channels : 45360**
(5×5 mm²)
- **Weight : ~ 700 Kg**

Design of Slab – Cross Section

The expected alveolar thickness is 6.5 mm **if**

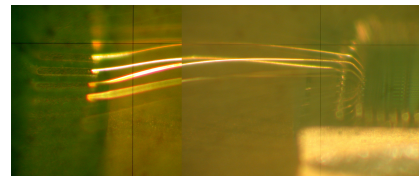
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Design EUDET Slab



- ⇒ Gaps (slab integration) : 500 μm ?
- ⇒ Heat shield : 400 μm ?
but real thermal dissipation ? (active cooling ?)
- ⇒ PCB : 800 μm (tolerances : \pm ?)
but chips embedded in PCB ?
- ⇒ Thickness of glue : <100 μm ?
study of the size of dots
- ⇒ Thickness of wafer : 320 μm – (\pm ?)
30 matrix ordered (90x90 mm²)
- ⇒ Kapton[®] film HV feeding :
100 μm - OK (*DC coupling*)
- ⇒ Thickness of W : 2100 μm (\pm 80 μm)

Chips and bonded wires inside the PCB



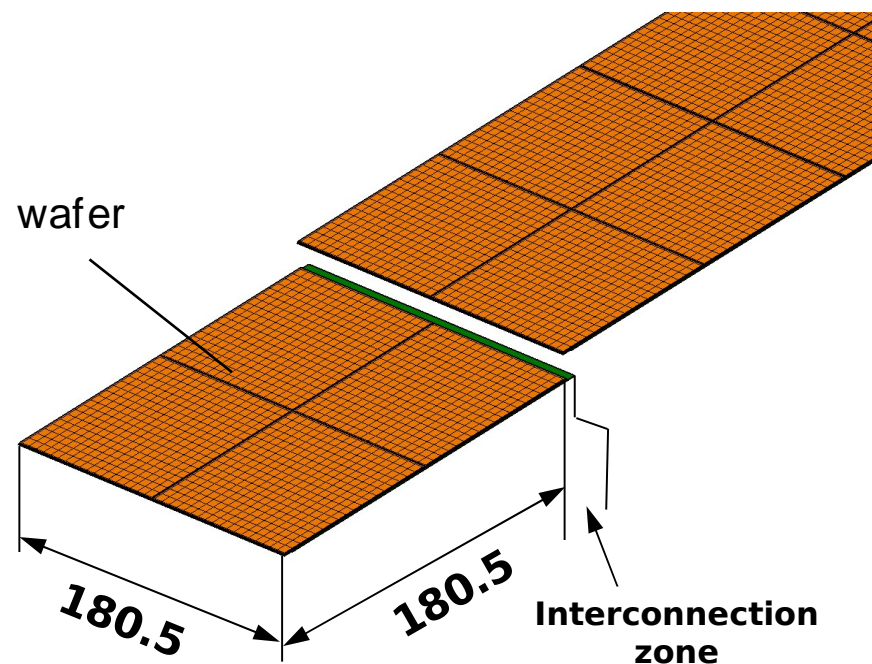
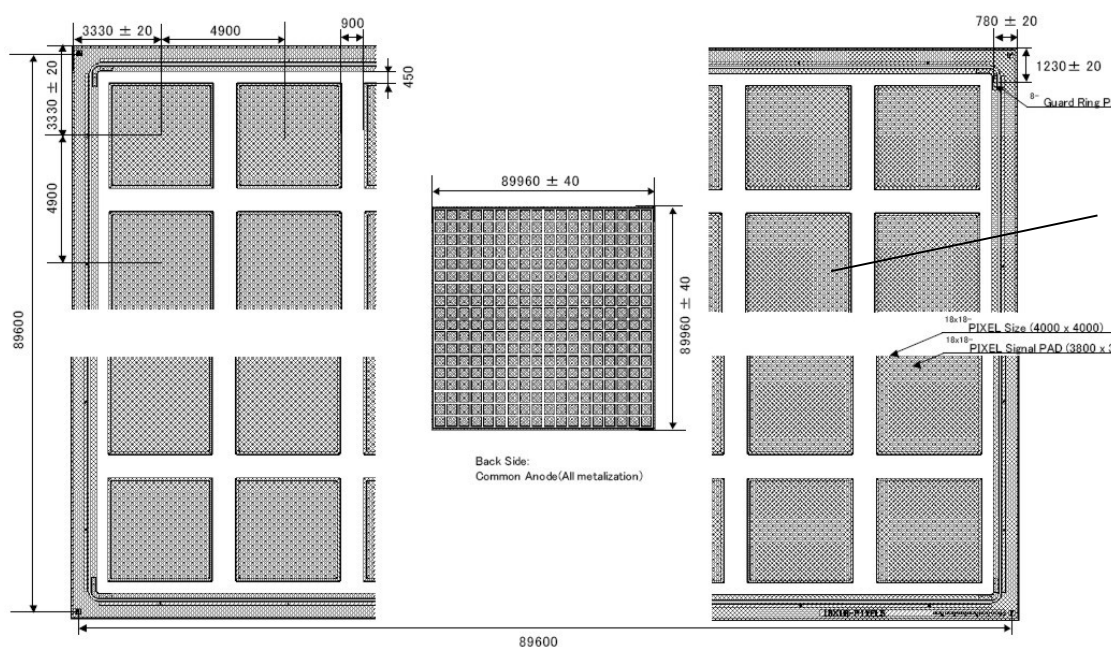
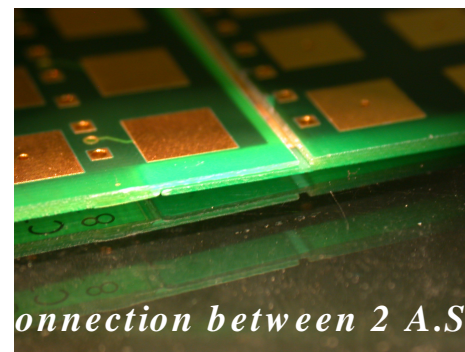
Several technological issues have to be studied and validated

Detector Slab Principle

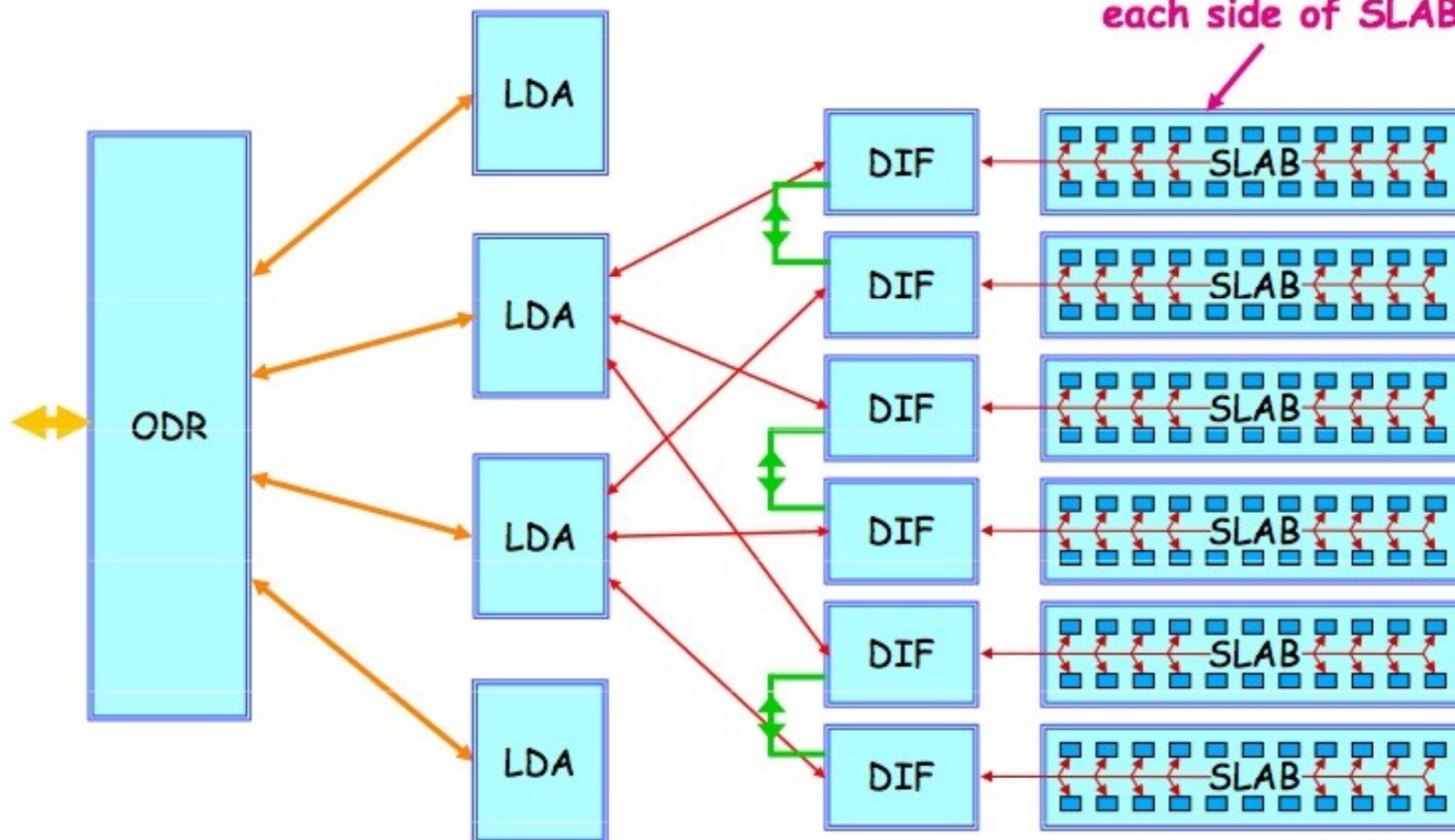
Long slab is made by several short PCBs :

A.S.U. : **A**ctive **S**ensors **U**nit

- Design of one **interconnection** « **inside** » PCB
- Easier development : study, integration and tests of A.S.U **in parallel** with other components of the project
- The **length** of each long slab will be obtained from the size of one “final PCB”



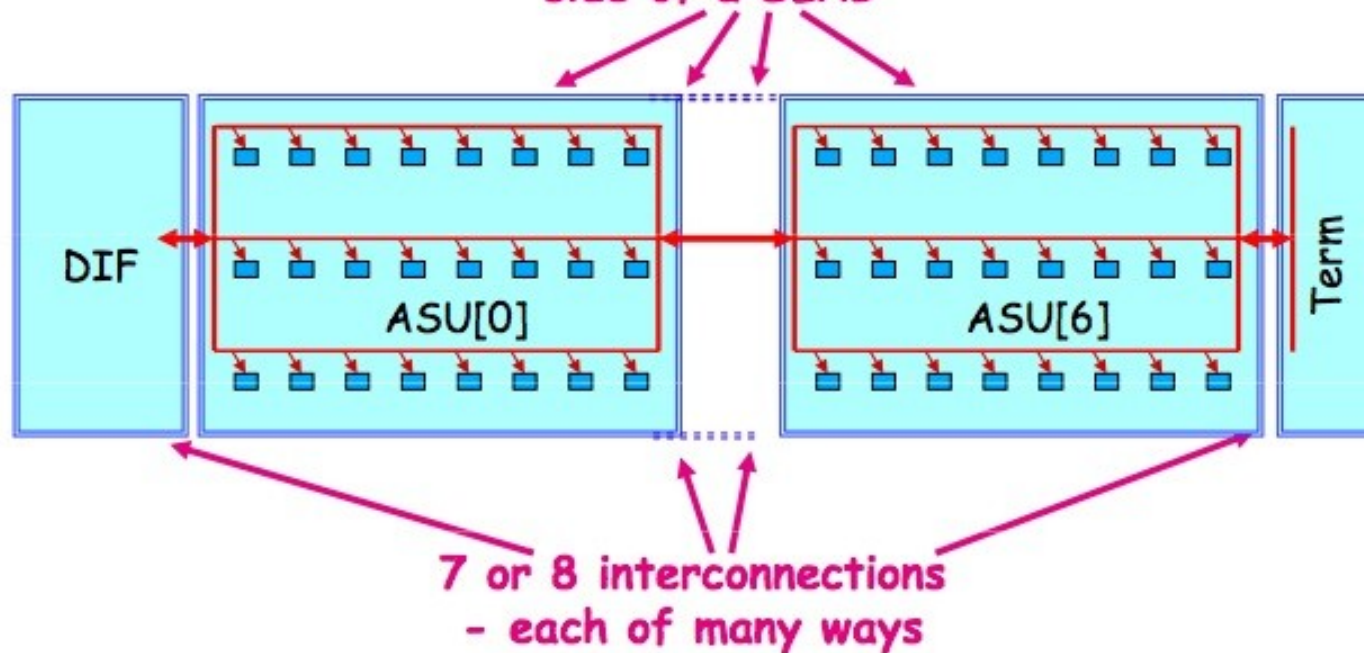
DAQ Architecture - Overall view ~150 VFE ASICs on each side of SLAB



Maurice Goodrick & Bart Hommels , University of Cambridge

Interconnections

6 or 7 ASUs on each
side of a SLAB



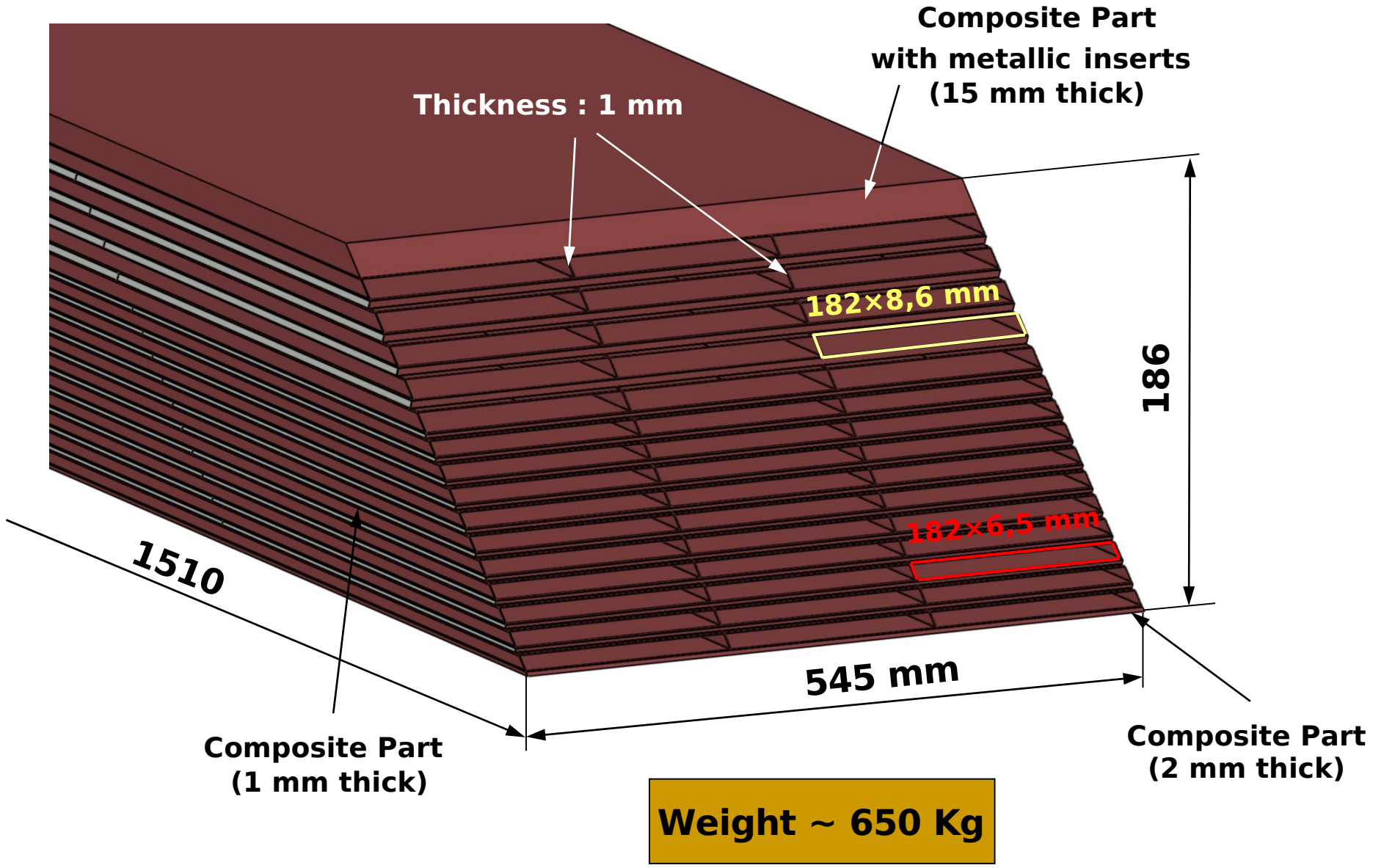
7 or 8 interconnections
- each of many ways

Options for Interconnection of ASU:

- glued joint step
- (glued) direct stitching
- FFC (Flat Flexible Cable)

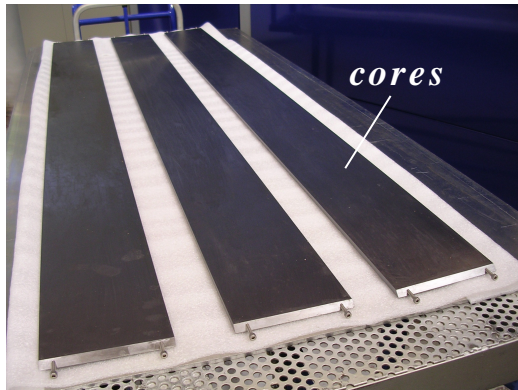
Read out Mode (Single line, multiple lines?)

Alveolar Structure 1/2

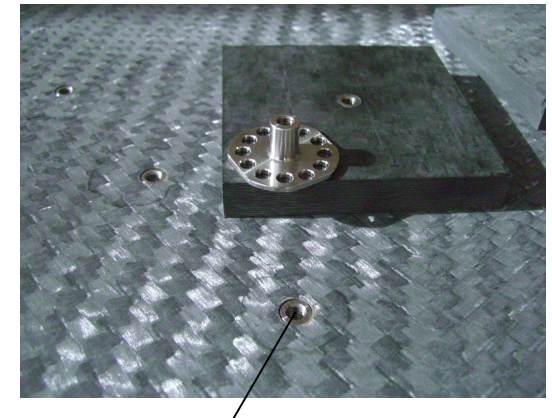
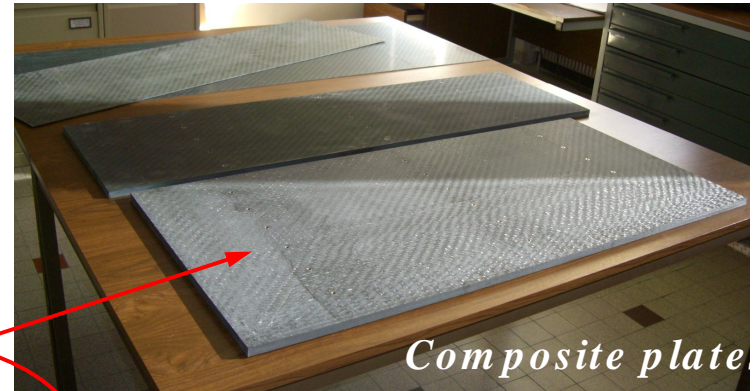
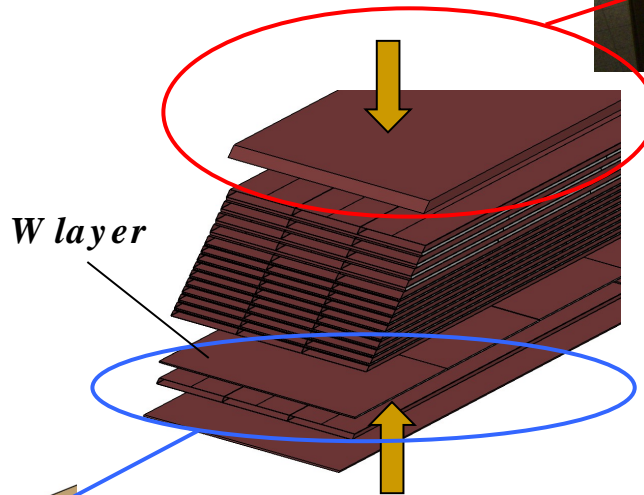
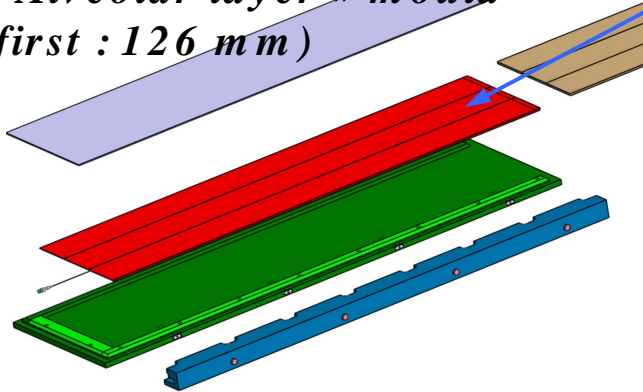


Alveolar Structure 1/2

Assembled structure : Each alveolar layer are done **independently**, cut to the right length (with 45°) and **assembled** alternatively with W plates in a second curing step
(2 width of cells : 126 mm and 182 mm)



« Alveolar layer » mould
(first : 126 mm)

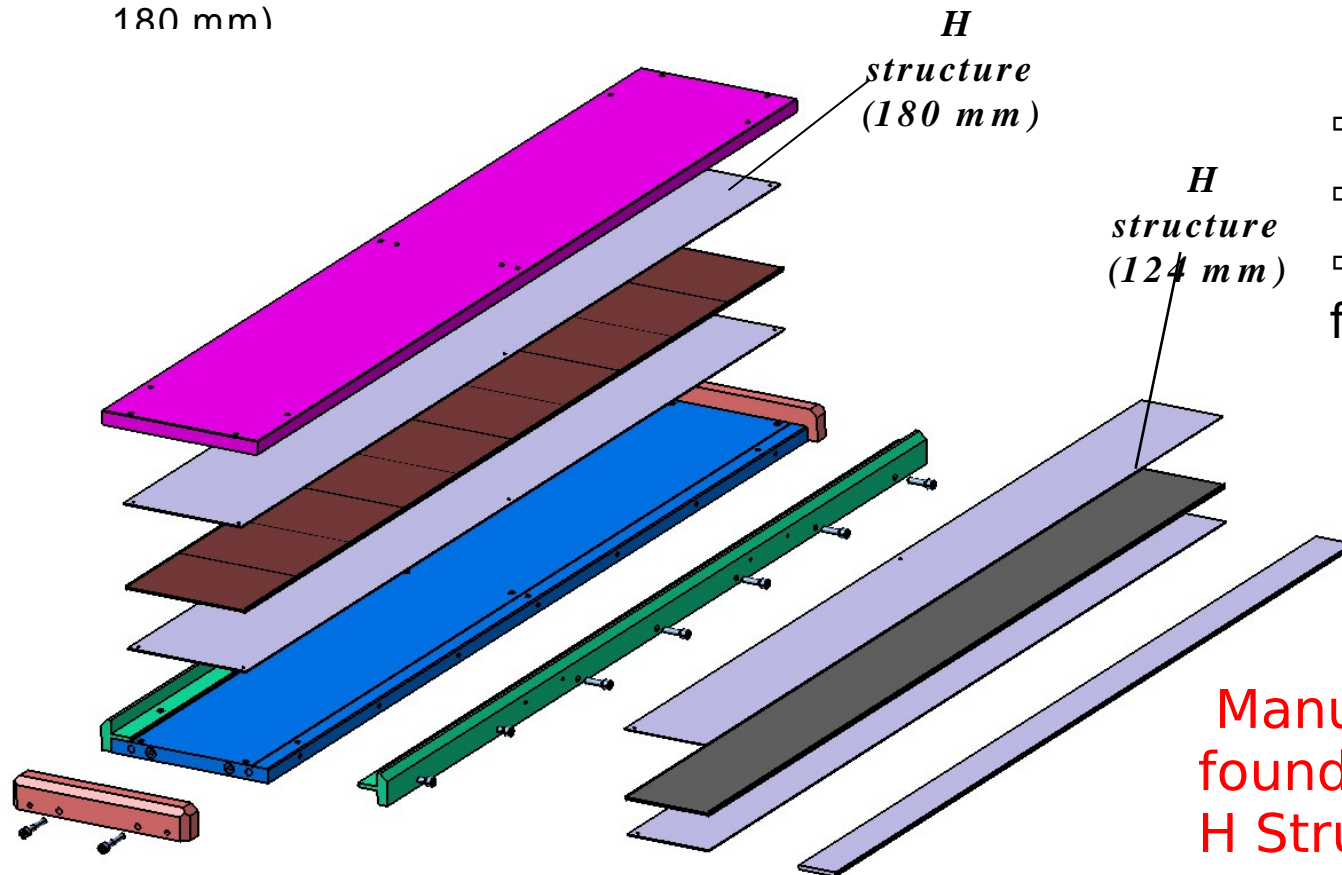


- ⇒ Global design : **OK**
- ⇒ “Alveolar layer” mould machining : **on going**
- ⇒ Design of assembly mould : **on going**
- ⇒ **Ready** : 4 composite plates (15mm and 2 mm)

Composite H Structure

Study and manufacturing of one mould for whole structures ([feb 2008](#)):

- Same principle than the mould used to do H physical prototype structures (autoclave)
- One long mould for both long and short H structures and 2 width (124 and 180 mm)



- ⇒ Design : OK
- ⇒ Quotation : on going
- ⇒ Ready (W + C) to mould first H structure (1300×124)

Manufacturer for long moulds found. Expect to have 124mm H Structure by April

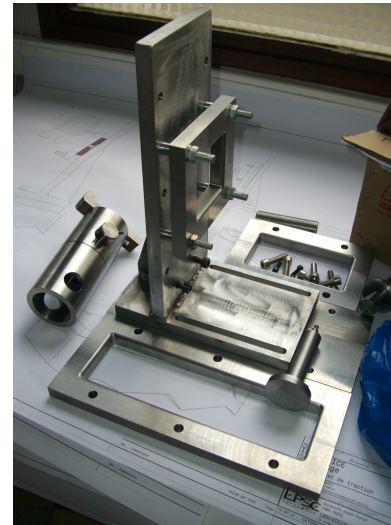
Important Milestone:

Manufacturing of Demonstrator holding (faked) PCB and Wafer units allowing for mechanical tests and thermal measurements until summer vacations

Destructive Tests

Mechanical tests of interface (feb 2008):

- **Destructive tests** of fastening elements: until breaking of interface in order to evaluate **constraints** and **elongations** under different loading cases:
 - Tensile / Compression
 - Cutting / Bending
- Study and fabrication of **testing tools**: OK
- Check and validate simulation results by **destructive tests** for each issues
- Similar type of tests to be performed for **characterization and calculation** of inter- alveoli thin sheets of composite



*tools for tensile
and compression
tests*



*Machine for
destructive tests*




Test pieces (interface)

Destructive Tests and Beyond

- Latest News -

Modules: *studies*

- *Finite Element Model of modules to estimate the overall deflection, with new cells 180x8.6 (common to CALICE end-cap studies).*
- *Optimization of composite sheets : studies of main parameters for thick plates*
- *Fasteners design (rails, facilitated insertion of modules) and inserts drawings : OK*
- *Cooling system and technology: Thermal study - design and test of heat pipes* 

Modules: *Tests*

- *Metrology and Machining tests of tungsten plates. OK*
- *Moulding of the composite parts 15mm & 2mm thick with metal inserts: OK*
- *Destructive tests on composite samples with inserts: OK*
- *Destructive tests on the mechanical interface ECAL/ HCAL : OK*
- *Prototype of the cooling system's connection kit for slabs : summer 2008...*
- *Fastening system ECAL/ HCA: rails: march 2008*
- *Destructive tests on the mechanical interface ECAL/ HCAL : april 2008*

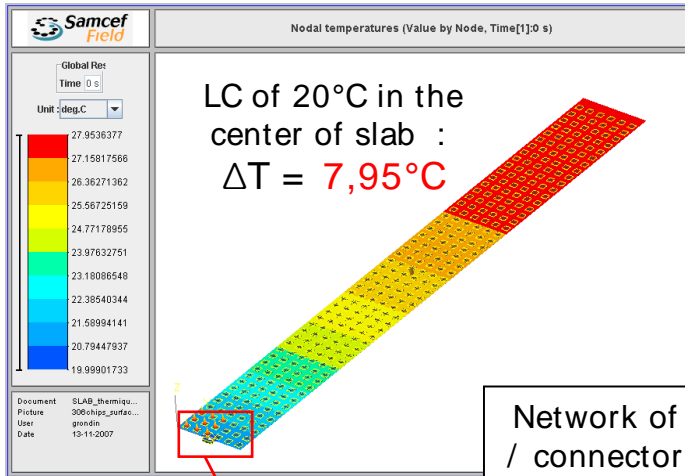
Confirmations are to be given for thermal studies: FPGA consumption and position...

Other studies & tests on going on Composite Structures & Services for **CALICE (End-Caps)**

Thermal Analysis of Slab

Simulation of heat conduction just by the heat copper shield :

Influence of the **FPGA dissipation** (DIF) on current design of cooling system
(Limit Condition of 20°C) :

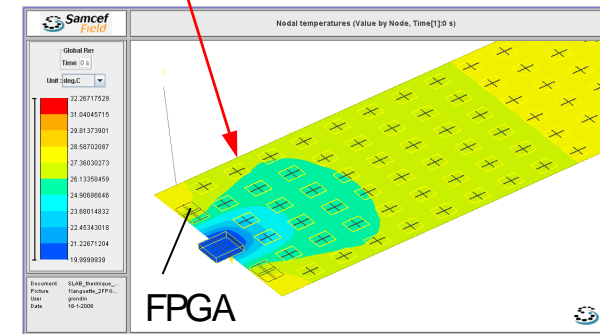
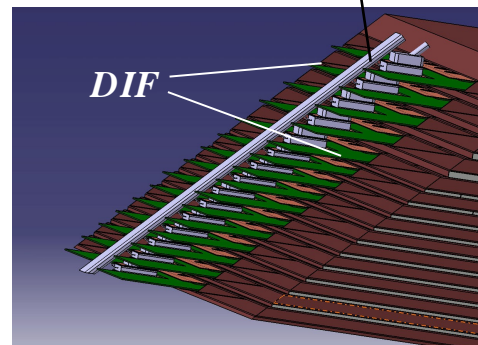
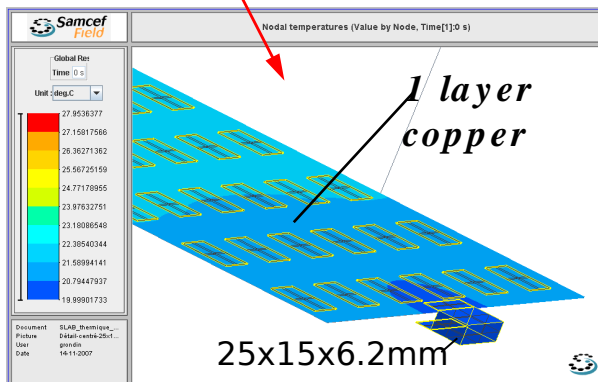
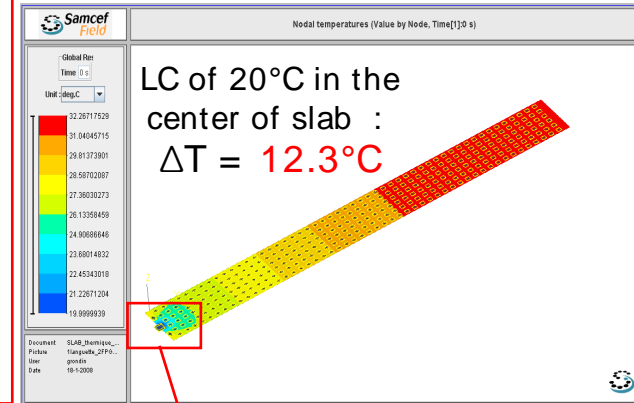


$\Phi = 0,27 \text{ W/layer}$
(25 μW per channel)
 $\Phi_{\text{FPGA}} = 3 \text{ W/layer}$

Copper layer : $\lambda = 400 \text{ W/m/K}$

$S = 180 \times 0.4 \text{ mm}^2$; $L =$
Cooling pipe

Network of contact areas / connector fixed on the 2 layers

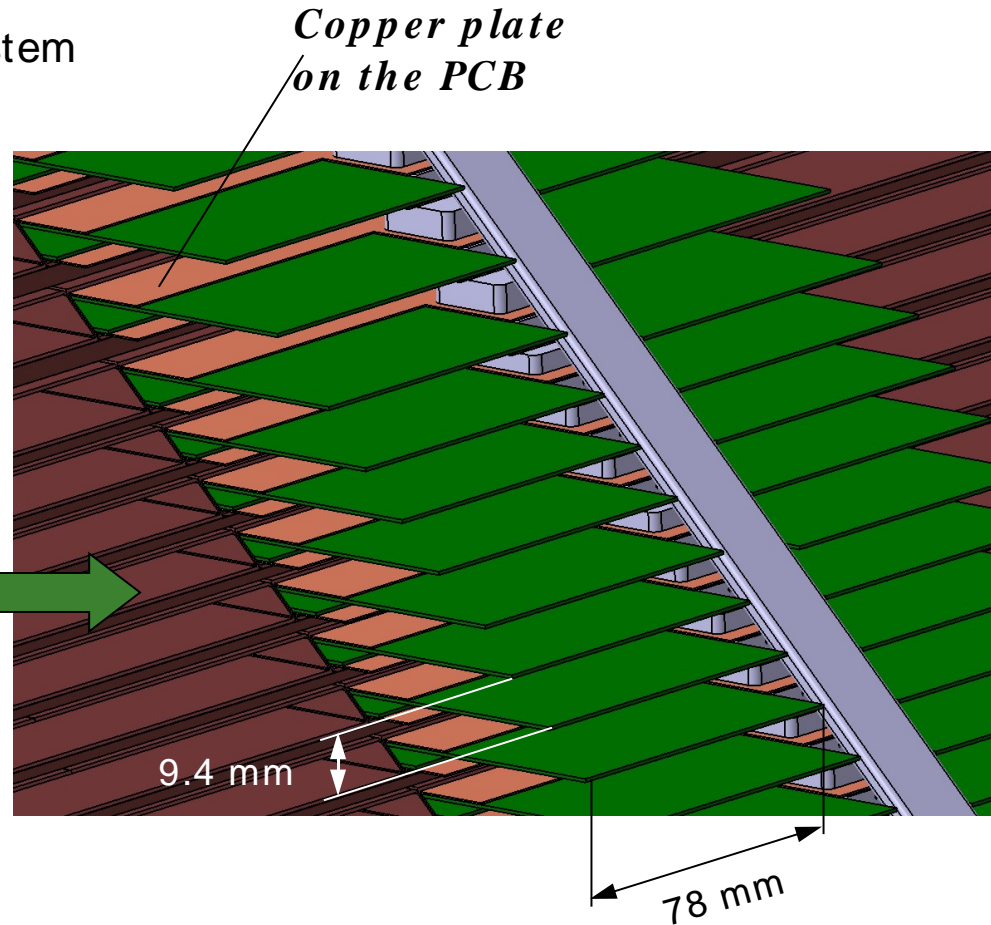
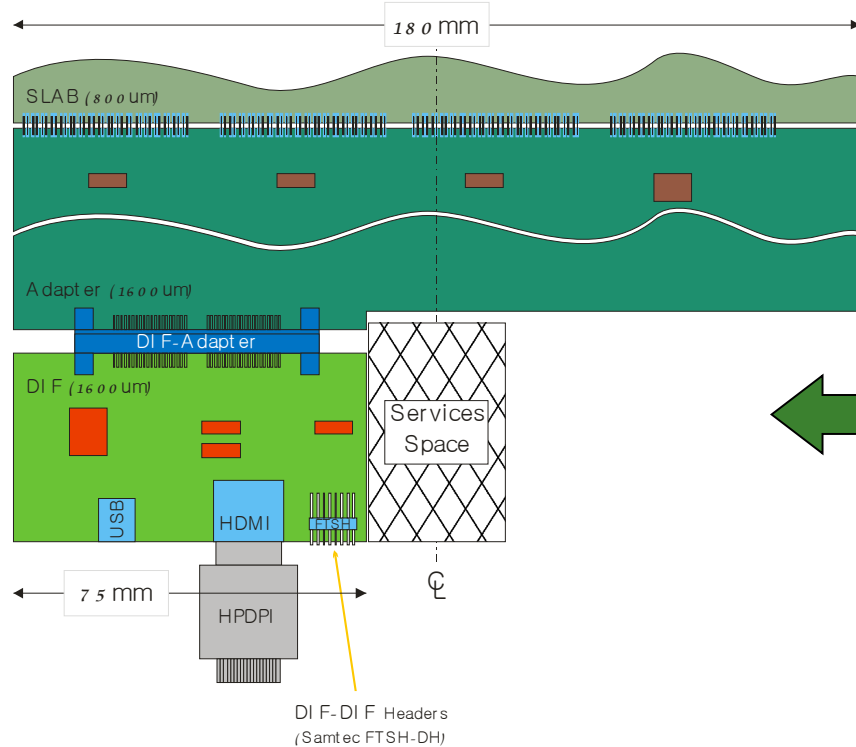


ΔT and **size** of cooling pipe **increase** ($\Phi T = 8.1 \text{ W}$ (SKIROC) to 98.1 W (SKIROC + DIF))

Interface SLAB <-> DIF

Current Module design **compatible** with this proposal from Cambridge?

- ❑ Adapter board (size, thickness ...)
- ❑ Components size
- ❑ Connectors size
- ❑ Fastening devices / back-end system
- ❑ Discussions with Julien?



(from Maurice Goodrick, Bart Hommels)

One of the biggest unknowns in the game!!!

Parties Involved

6 Laboratories are sharing out tasks in according to preferences and localization:

MANCHESTER 1824 Assembling of **A.S.U.** (industrialization, gluing and tests) + backend system (DIF support) + services



Tests of **wafers**
Global **Design** + composite **Structures**



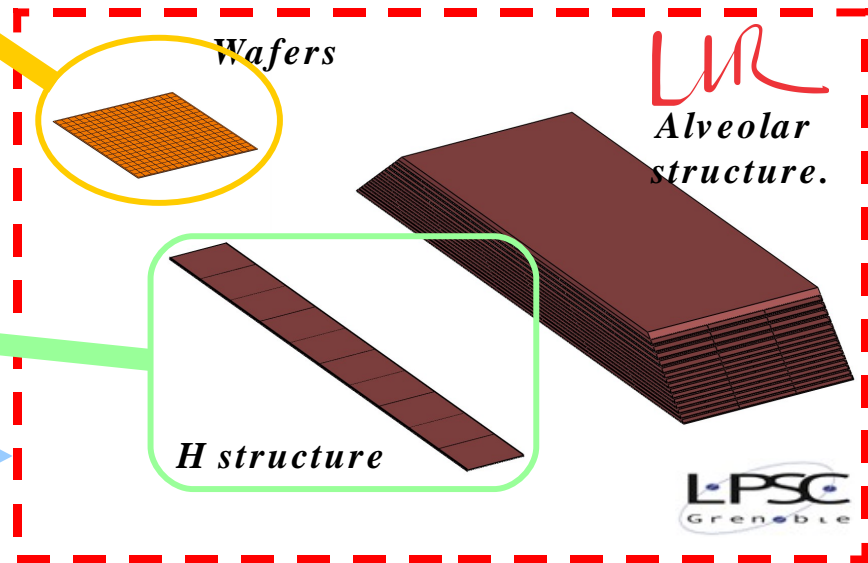
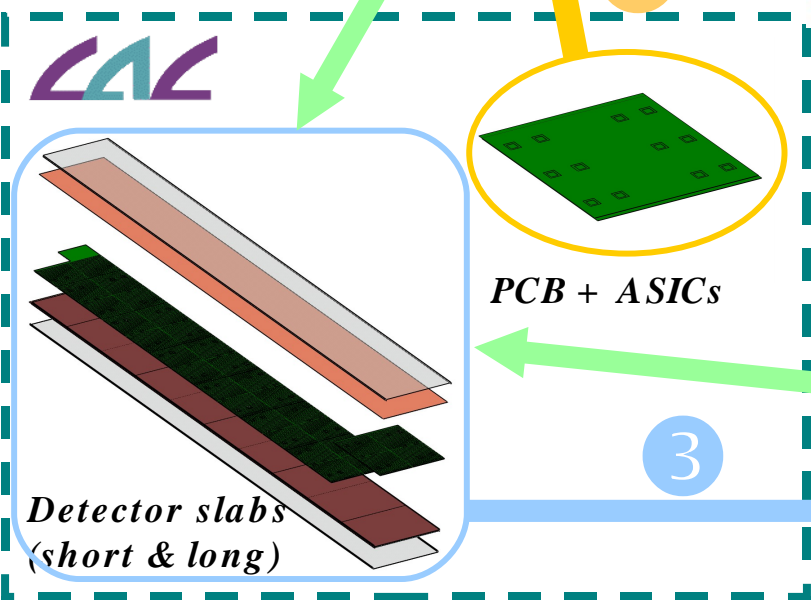
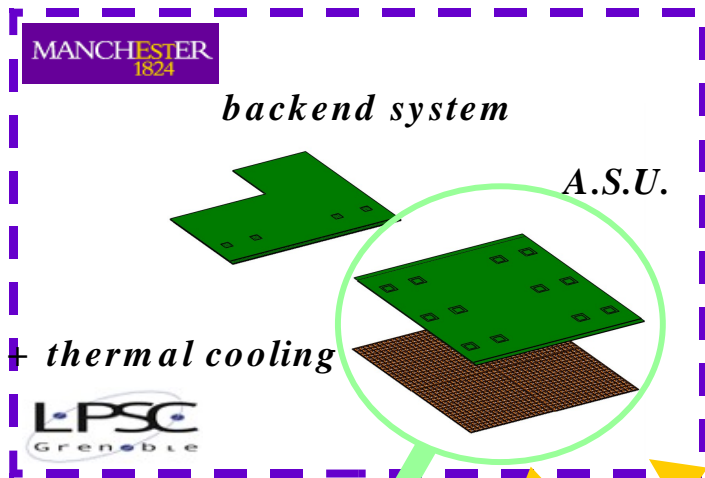
Thin PCB with embedded ASICs
Detector slabs integration



External cooling system (+ Manchester)
Fastening system ECAL/HCAL+composite plates



Interconnection of ASU, DIF(?)



2

1

2

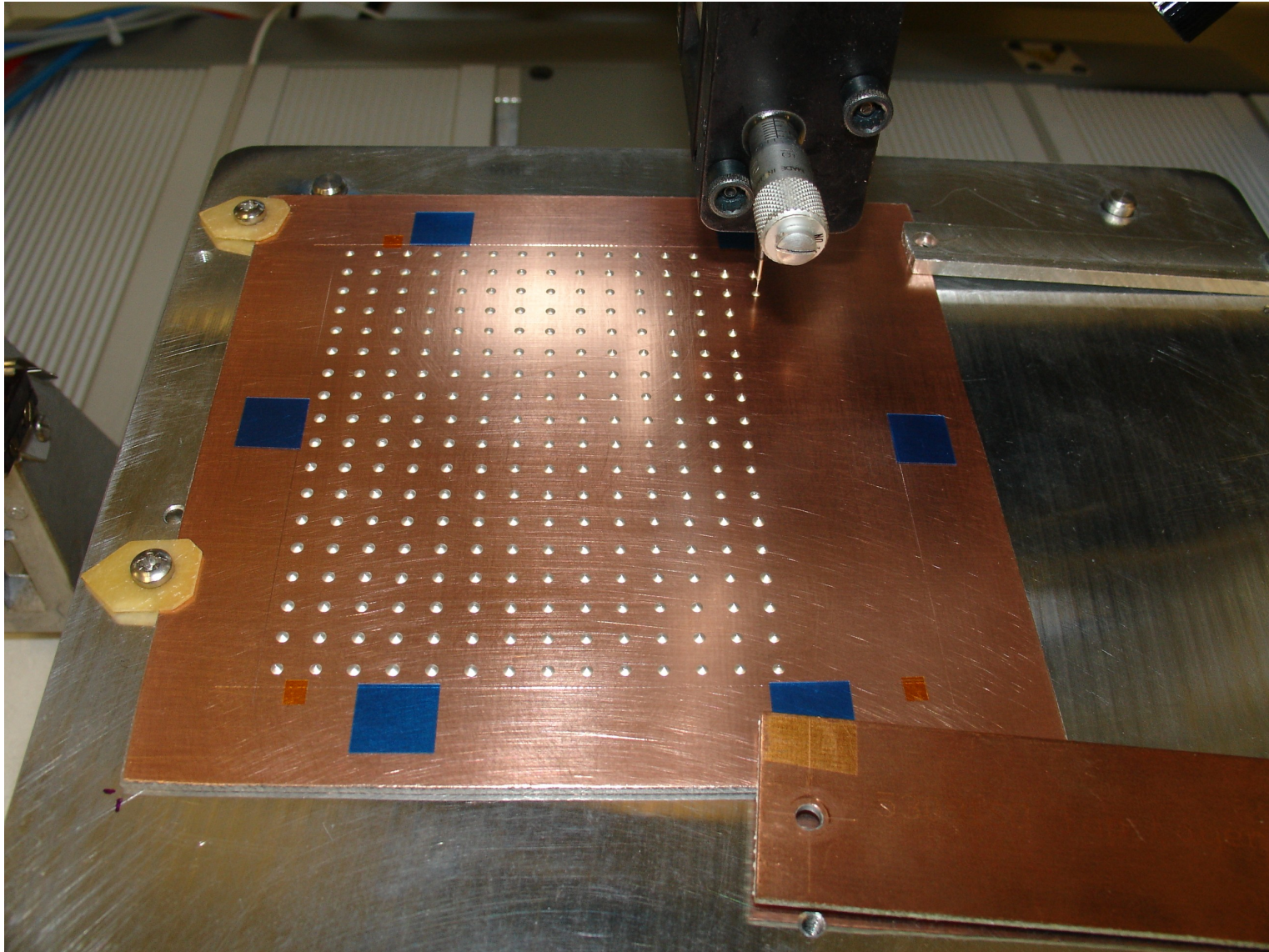
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Status of Wafer Production

- 20 Wafers to be expected from Hamamatsu expected by Middle of April
 - 90x90mm² wafers for 324 cells per wafer
 - 5x5 cell size
 - => 324 Cells/wafer
- Immediate start of Characterisation
 - Leakage Current (I-V curves)
 - Full depletion Voltage (C-V Curve)
- Can be used to test gluing with 'real' wafers
(Depends on speed of Characterization Tests and quality of Wafers)
- On going: New designs of guard ring
 - > Talk by Francois

Mechanical/Electrical Connection between Wafer and PCB – Gluing To

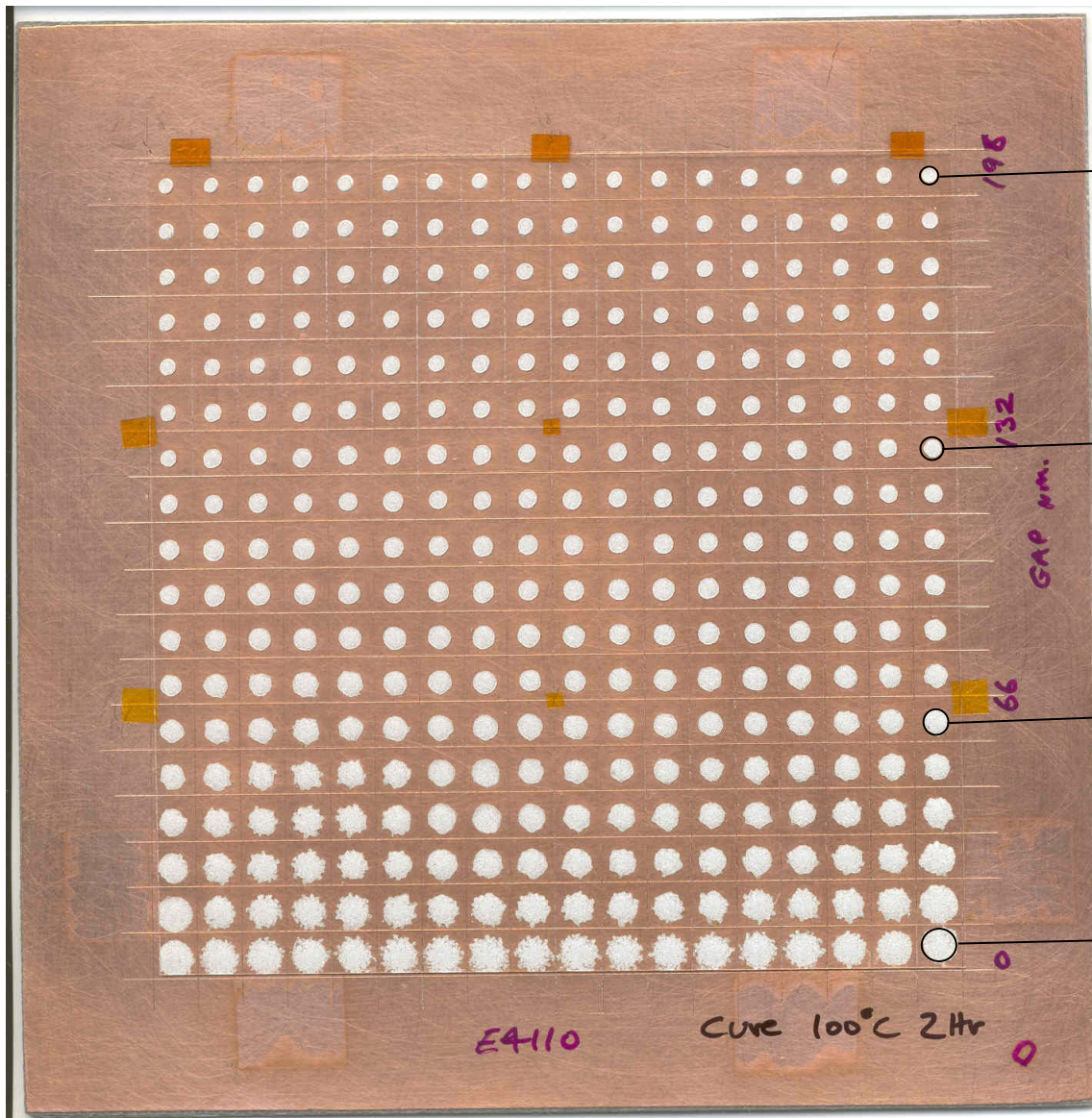
Using simple glass plates to mimic wafers



Placing glue dots

18 x 18 (324) dots on 5mm grid takes ~5min

Galice Collaboration ANL March 2008



Wedge Shaped Glass Plate

Ø1.6 mm

200 μm

space between
glass and pc board

Ø2.0mm

132 μm

space between
glass and pc board

Ø2.5mm

66 μm

space between
glass and pc board

Ø3.6mm

zero

space between
glass and pc board

Glass Plate #2

0.2 sec per dot

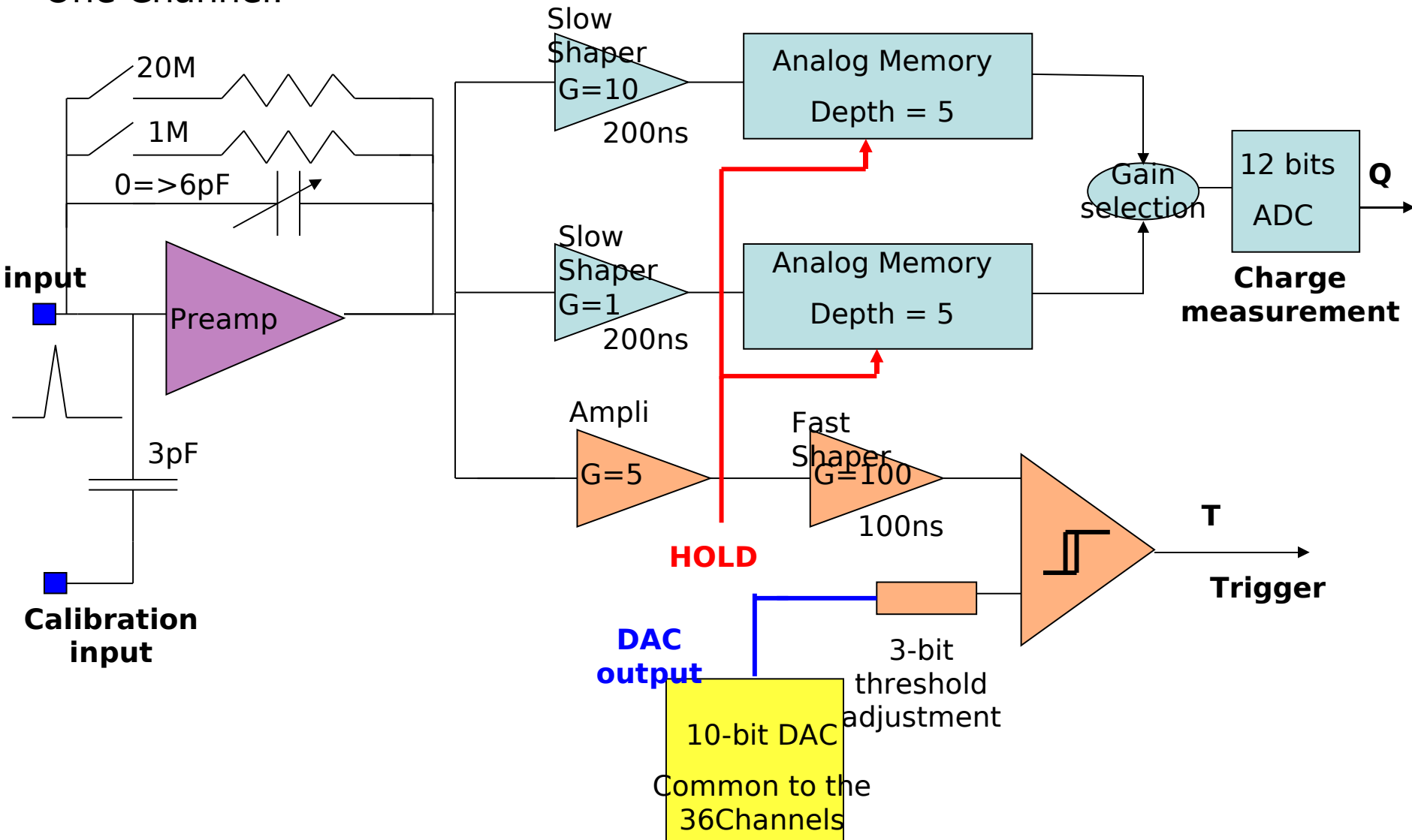
Mid spacers under
plate

Net Conclusion: Gluing of tight wafer matrix can be done

Dot thickness/width influences resistivity: Diameter control within 50 μm seems feasible

SKIROC Chip

One Channel:

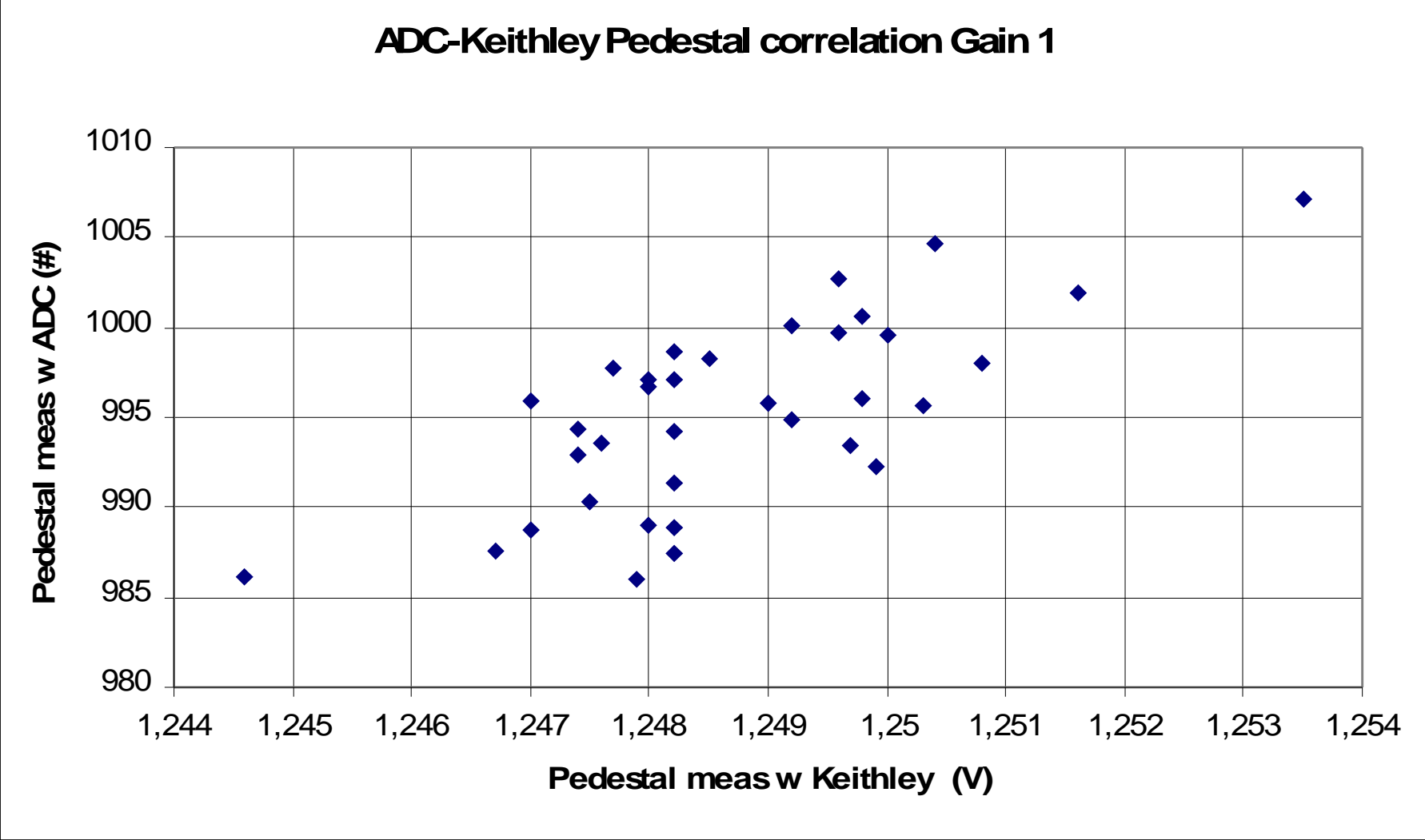


Test with 36 Channel Chip

SKIROC Chip still in design phase mainly due to high demands on compactness

Pixel Calorimeter is challenging technology

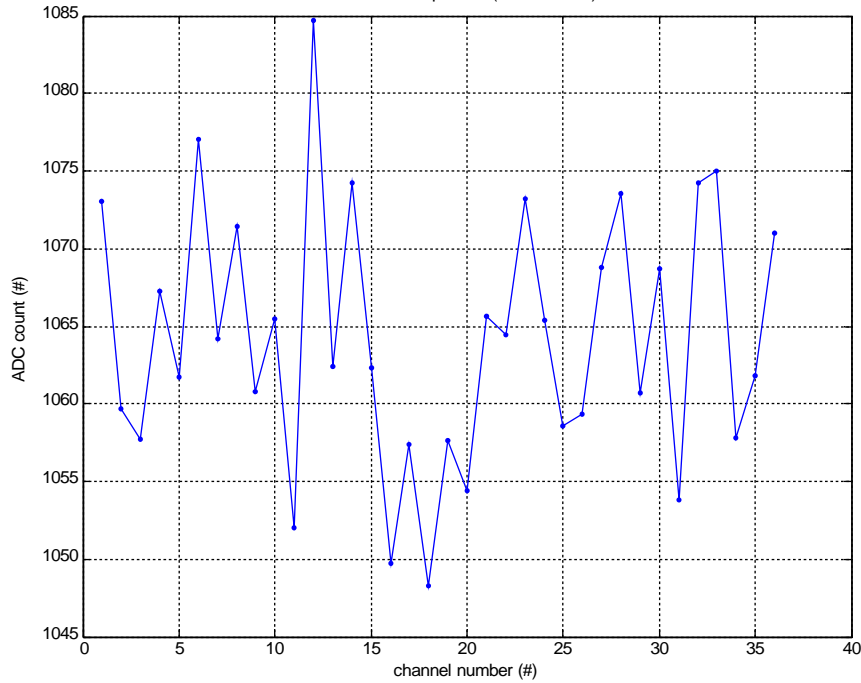
SKIROC Measurements



Independent measurements of pedestals compatible

SKIROC Pedestal Dispersion – Gain 1

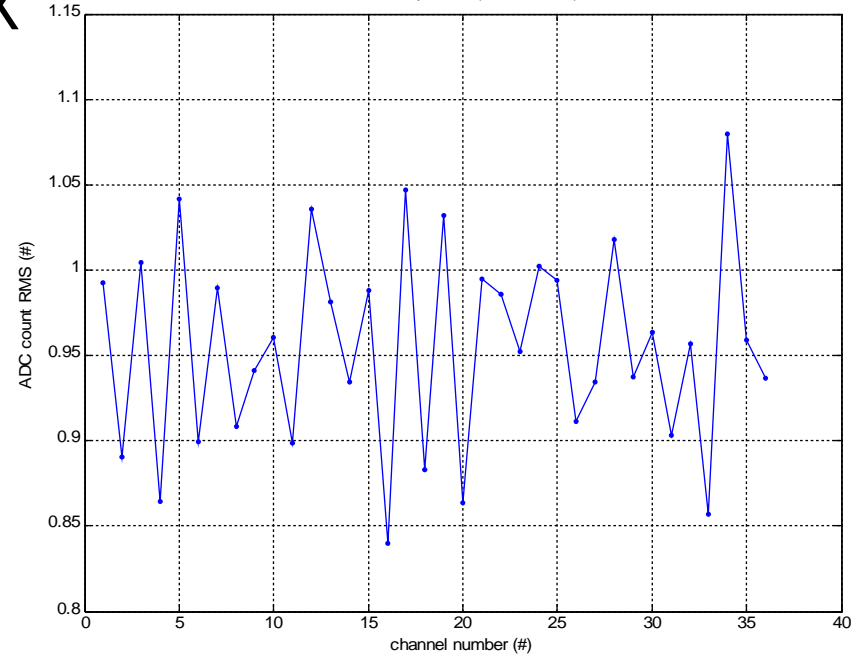
Skiroc Pedestal Dispersion (Internal ADC)-Gain 1



SKIROC Noise Dispersion – Gain 1

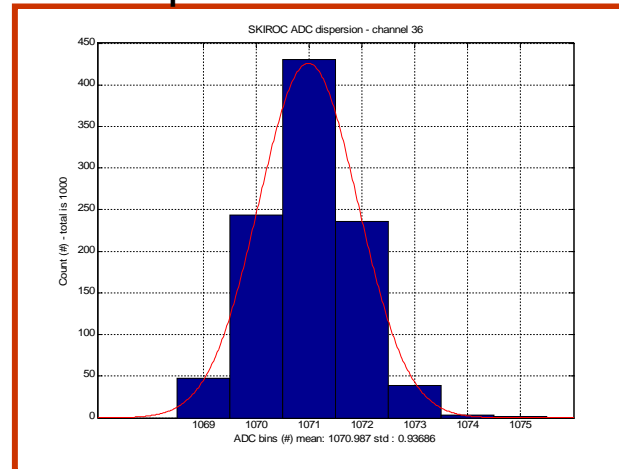
Skiroc Noise Dispersion (Internal ADC)-Gain 1

X



Random Distribution
of Pedestals

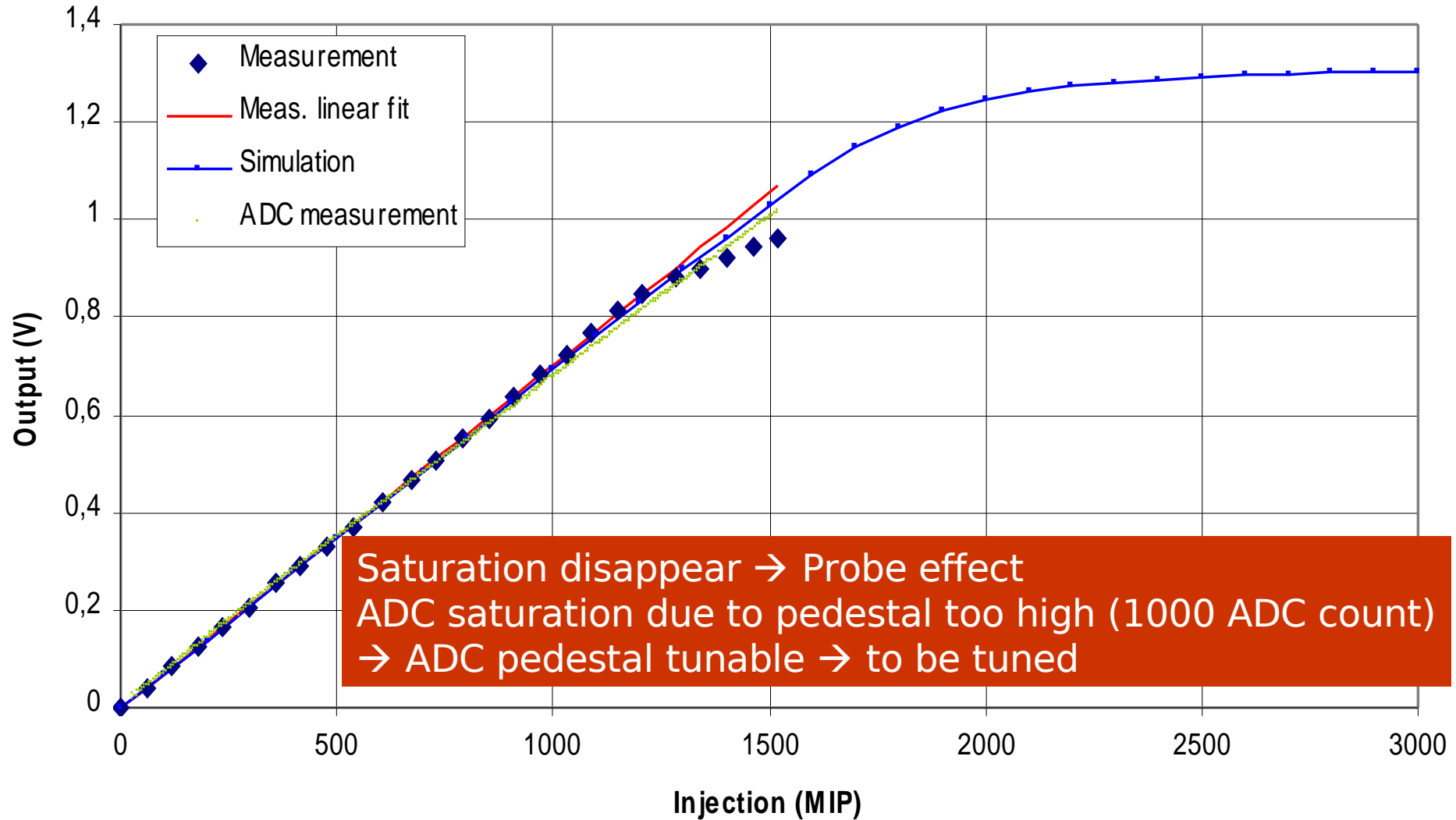
Example for one channel



Gaussian Noise
~0.95 ADC Counts = 330 μ V

SKIROC - Linearity

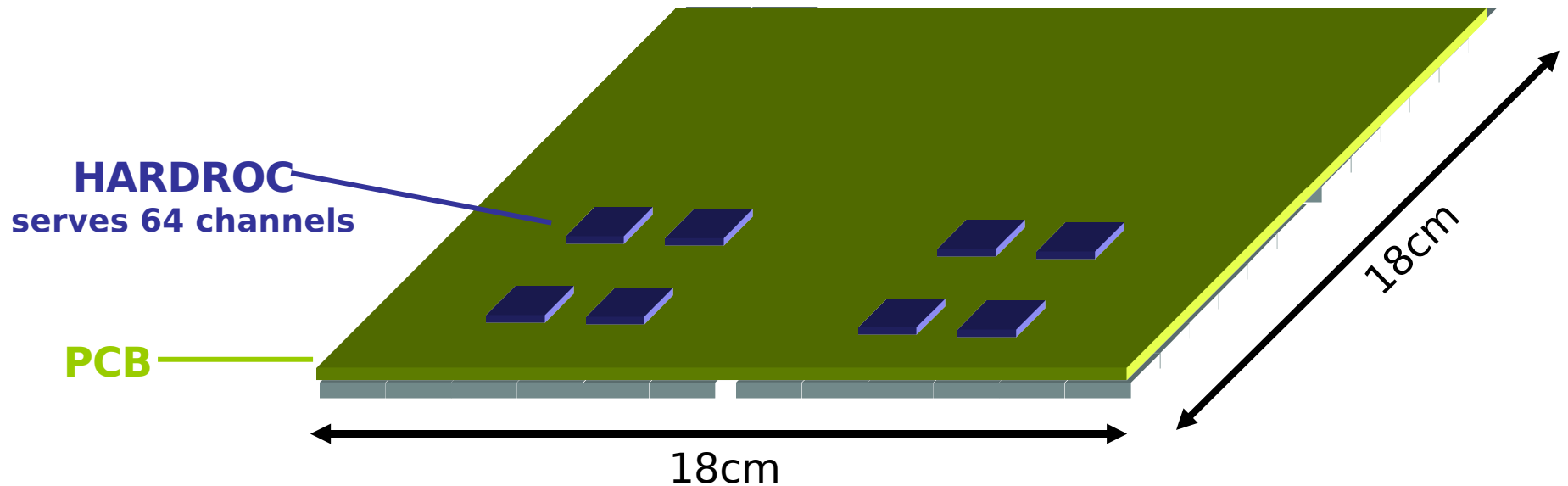
SKIROC linearity results



- Saturation also observed in independent measurements
- Effect about to be understood

PCB Design: Towards FEV5 – First steps ...

Use HARDROC Chip (for EU-DHCAL) to advance in PCB design



- PCB to be designed for 1296 Pads (=4 Wafer à 324 Pads)
- High degree of compactness

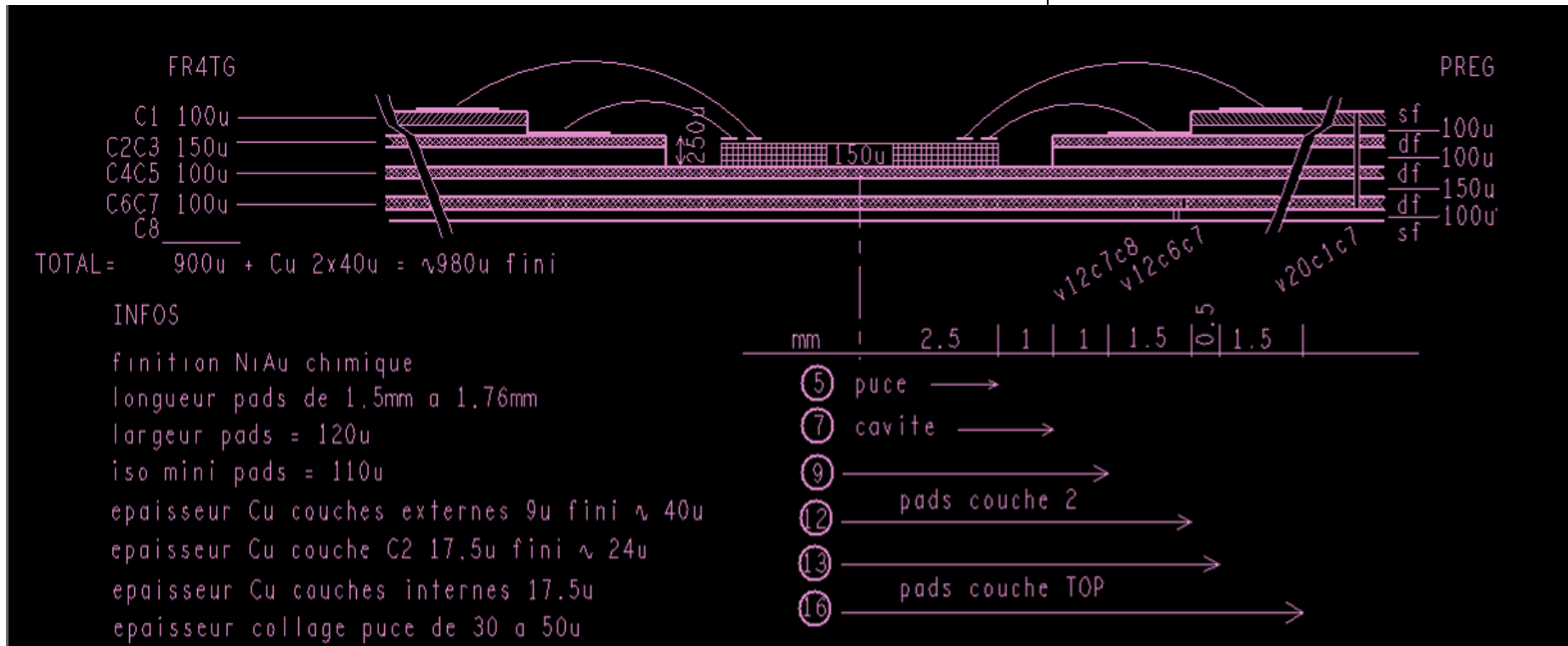
Chip Integration in PCB

Pile-up

TOP	GND+routing
C2	AVDD+routing
C3	AVDD+DVDD
C4	GND + horizontal routing
C5	AVDD+ vertical routing
C6	GND+pads routing
C7	GND (pads shielding)
BOT	PADS





3 drilling sequences :

- Laser C7-C8 120μ filled
- Laser C6-C7 120μ
- Mechanical C1-C7



- Bonding wires from Chip to PCB challenging due to large number of channels
- Has to fit into overall mechanical tolerances (see above)

Schedule (Taken from Marc Anduze)

	<p>Assembling of A.S.U. (industrialization, gluing and tests) :</p> <ul style="list-style-type: none"> first gluing studies (glass on PCB) first resistive tests according to the size of the dot Backend system (DIF support) Services (cooling system participation ?) 	<p>March 08 March 08 Jan 09 ? Jan 09 ?</p>
	<p>Tests of wafers :</p> <ul style="list-style-type: none"> reception 30 first wafers set-up (“mechanical box”) <p>Global Design</p> <p>Composite Structures :</p> <ul style="list-style-type: none"> mould + first H structure (126 mm) “alveolar layer” mould + first layer assembly mould demonstrator (2 or 3 layers – 126mm) 	<p>April 08</p> <p>March 08 April 08 June 08 Sept 08</p>
	<p>Thin PCB with embedded ASICs</p> <p>Detector slabs integration</p>	<p>Jan 09 ? Jan 09 ?</p>
	<p>External cooling system (+ Manchester)</p> <p>Fastening system ECAL/HCAL</p> <p>composite plates</p>	<p>June 08 March 08 Feb 08</p>

Lot's to be done

Calice Collaboration ANL March 2008